

PIVOTAL

S Y S T E M S

GFC5L™
GFC20L™
GFC50L™

The Future of
Flow Control



Wide Flow Range

2.0–100% Full Scale

Flow Accuracy

*±1.0% of Setpoint for 10% -100% Full Scale
±0.25% of full scale for 2.0–10.0% Full Scale*

Fastest Settling Time for Turn-On and Turndown *≤300ms 10%- 100% F.S.*

Innovative Control Technology

Robust Design, No Orifice

Introduction

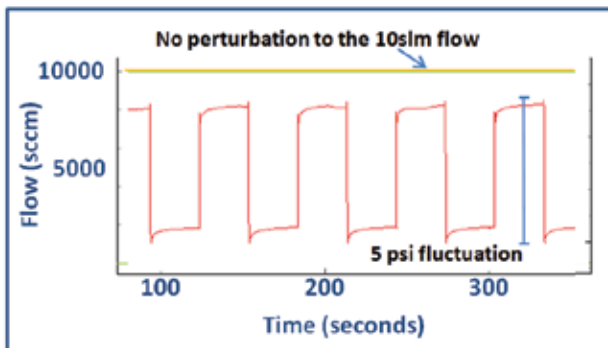
As process geometries within the semiconductor industry continue to shrink to 10 nm and beyond, the need for highly accurate, responsive and repeatable gas flow control during wafer processing is essential. With the emergence of low gas flow rates, short processing times and continuous plasma processing, best-in-class MFCs are struggling to meet the accuracy, settling time and repeatability requirements demanded to ensure high yield and matched chambers.

Pivotal Systems' high flow GFC paves the way for the future of gas flow control. The high flow GFC combines a differential pressure with patented control valve technology. As such, it leapfrogs the current MFC technology by offering an order of magnitude improvement on key flow metrics, thereby enabling advanced wafer-manufacturing processes.

Feature Description

Pressure and Temperature

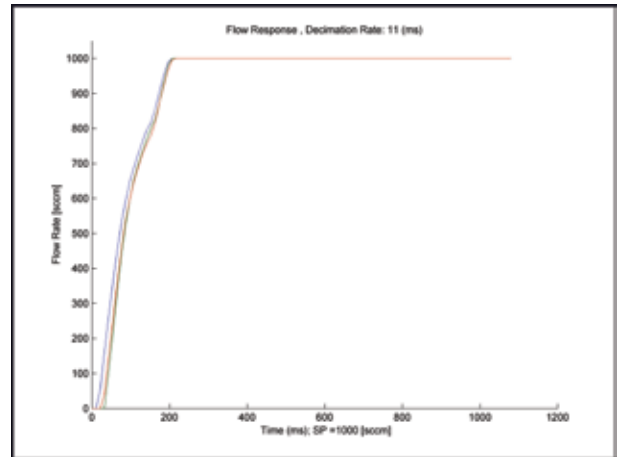
The unique design of the Pivotal valve results in the HFC being unaffected by variations in the upstream or downstream pressure or temperature. The high flow GFC does not need a temperature coefficient. Highly sensitive sensors monitor the gas pressure and temperature every milli-second and the control scheme accounts for any variations.



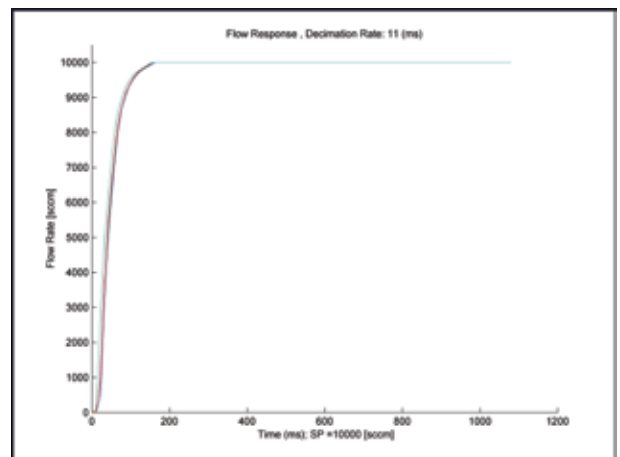
Settling Time

The high flow GFC offers best-in-class settling times for flow controllers by providing settling times below 300 ms for both the gas turn-on and gas turn-down. Refer to the following graphics.

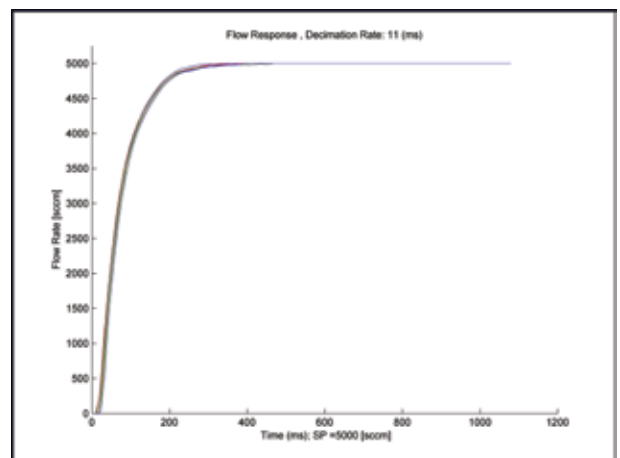
0 to 20 slm Turn on Time



0 to 10 slm Turn on Time



0 to 5 slm Turn on Time



GFC Specifications

Performance	Flow range	100 sccm - 50000 sccm (3 part numbers cover this range)
	Flow Accuracy	±1% of setpoint for 10%-100% FS : 0.5 slm - 5 slm (GFC-5L), 2.0 slm - 20 slm (GFC-20L), 5.0 slm to 50 slm (GFC-50L) ±0.25% of setpoint for flows 2% to 10% of FS : 0.1 slm - 0.5 slm (GFC-5L), 0.4 slm - 2.0 slm (GFC-20L), 1.0 slm - 5.0 slm (GFC-50L)
	Settling Time	≤300 ms 10% - 100% FS, ≤ 500 ms 2% - 10% FS *
	Leak Integrity	≤ 5E ⁻¹² Pa*m ³ /sec (He)
	Leak By Rate	25.0 sccm (GFC50L), 2.5 sccm (GFC5L), 10.0 sccm (GFC20L),
Operation Conditions	Supply Pressure	Standard: 276 - 448 kPaG (40 - 65 psig)
	Downstream Pressure	Vacuum to 101 kPa (0 - 760 Torr)
	Proof Pressure	2.07 MPaG (300 psig)
	Operation Temperature	15 – 50°C
Materials	Wetted Surface	316 SS per Semi F20
	Surface Finish	5 µin average Ra
	Seals	Metal
Electrical	DeviceNet	11 – 24 VDC, 5 W
	Analog and RS-485	±15 VDC; 150 mA
	In-Rush Current	<200 mA

* There is a setpoint hold-time of 60 milliseconds during Analog control. This time is in addition to the reported settling time of this device. When running using Analog control, the GFC has a minimum setpoint sensitivity of ±50mV. The flow accuracy is unaffected. The measured setpoint and corresponding flow feedback may be different from the commanded setpoint by up to that amount. Analog calibration is recommended to align device input to the controller output.

Gas Bin Table

Title Gas	Gas #	Bin 10: 5L			Bin 20: 20L			Bin 30: 50 L			Input Pressure Range (psig)	Max Downstream Pressure (Torr)
		Min Flow	FS Setting		Min Flow	FS Setting		Min Flow	FS Setting			
			Min	Max		Min	Max		Min	Max		
N2	13	100	2001	5000	400	5001	20000	1000	20001	50000	35 - 65	760
Ar	4	100	2001	5000	400	5001	20000	1000	20001	40000	35 - 65	760
CO2	25	100	2001	5000	400	5001	10000	1000	10001	25000	35 - 65	760
H2	7	400	5001	20000	1000	20001	50000	-	-	-	35 - 65	760
He	1	400	5001	20000	1000	20001	50000	-	-	-	35 - 65	760
O2	15	100	2001	5000	400	5001	20000	1000	20001	40000	35 - 65	760
N2O	27	100	2001	5000	400	5001	10000	1000	10001	25000	35 - 65	760
NF3	53	100	2001	5000	400	5001	10000	1000	10001	25000	35 - 65	760
Mixed 4% H2 in N2	607	100	2001	5000	400	5001	20000	1000	20001	50000	35 - 65	760

Product Description Code

Code	Description	Option	Option Description												
I	Base Model	GFC	Gas Flow Controller												
II	Special Application	XX	Standard Application												
		LP	Low Pressure Gases												
III	Configurability	C	Multi-gas Standard Bins												
		X	Gas Configured												
IV	Gas or Standard Bins	XXXX XXXX	Specific Semi Gas Code and Range												
		PS10 005L	Pivotal Systems Standard Bin 04 2001-5000 sccm N2 **												
		PS20 020L	Pivotal Systems Standard Bin 05 5001-20000 sccm N2 **												
		PS30 050L	Pivotal Systems Standard Bin 06 20001-50000 sccm N2 **												
V	Fitting & Body Width	01	VCR 1.125"												
		02	C-Seal 1.125"												
		03	W-Seal 1.125"												
VI	Valve Configuration	C	Normally Closed												
VII	Downstream Condition	V	Vacuum												
		A	Atmospheric - This option can be used for all gases except low pressure gases. Inlet pressure must be ≥60 psia												
VIII	Communication Options	Option	I/O	Connector	Power on State	Full Scale Setting	Full Scale Setting	Full Scale Setting	Pull I/O Instance Producer	Pull I/O Instance Consumer	Poll I/O State Transition	SP Delay in ms	External Baud Rate	Mac ID	
		DA	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	2	7	Executing	0	500KB	63	
		DB	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	21	7	Executing	0	500KB	63	
		DC	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	2	8	Executing	0	500KB	63	
		DD	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	21	8	Executing	0	500KB	63	
		DE	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	6	8	Executing	0	500KB	63	
		DF	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	22	7	Executing	0	500KB	63	
		DG	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	3	7	Executing	0	500KB	63	
		DH	DeviceNet	5 Pin Micro	Idle	Count	Integer	7FFFh	3	7	Executing	0	500KB	63	
		DI	DeviceNet	5 Pin Micro	Idle	SCCM	Float	6000h	14	19	Executing	0	500KB	63	
		DJ	DeviceNet	5 Pin Micro	Idle	SCCM	Float	6000h	23	20	Executing	0	500KB	63	
		DK	DeviceNet	5 Pin Micro	Idle	SCCM	Float	7FFFh	13	19	Executing	0	500KB	63	
		DL	DeviceNet	5 Pin Micro	Idle	Count	Integer	7FFFh	6	8	Executing	0	500KB	63	
		DM	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	2	7	Executing	0	500KB	63	
		DN	DeviceNet	5 Pin Micro	Idle	Count	Integer	7FFFh	22	7	Executing	0	500KB	63	
		DO	DeviceNet	5 Pin Micro	Idle	Count	Integer	6000h	22	8	Executing	0	500KB	63	
		DP	DeviceNet	5 Pin Micro	Idle	Count	Integer	7FFFh	3	7	Executing	500 ms	500KB	63	
		DQ	DeviceNet	5 Pin Micro	Idle	Count	Integer	7FFFh	1	8	Executing	0	500KB	63	
		EA	Ethercat	Comm: RJ45 Pwr: 5 pin Nano	INIT	NA	NA	NA	NA	NA	NA	NA	NA	NA	0
		RA	RS-485	9-Pin D	NA	NA	NA	NA	NA	NA	NA	NA	NA	115200	63
		RB	RS-485	9-Pin D	NA	NA	NA	NA	NA	NA	NA	NA	NA	115200	63
		RC	RS-485	9-Pin D, RJ45	NA	NA	NA	NA	NA	NA	NA	NA	NA	115200	63
		Analog DB9 Pin-Out													
		Option	I/O	Connector	Valve Override	Flow Feedback	Power Supply +	Power Supply Common	Power Supply -	Flow Setpoint	Signal Ground	RS 485 +	RS 485 -	Test Point	
		AA	Analog	9-pin D	1	2	3	4	5	6	7	8	9	NA	
		AB	Analog	9-pin D	1	2	3	4	5	6	7, 8	NA	NA	9	
		AC	Analog	20-pin Honda	14	3	4	2	16	11	12	8	9	NA	
AD	Analog	20-pin Honda	14	3	4	2	16	5	12	8	9	NA			
AE	Analog	Card Edge	NA	3	4	2	F	A	B+C	NA	NA	NA			
AF	Analog	Card Edge	D	3	4	2	F	A	B+C	NA	NA	NA			
AG	Analog	Card Edge-RJ11	J	3	4	2	F	A	B+C+10	3, 4	2, 3	NA			
AH	Analog	DB9 to DB15	NA	NA	7	5	5	8	NA	NA	NA	NA			
AJ	Analog	DB9 to DB15	NA	2	7	5	6	8	11, 12	NA	NA	NA			
IX	Special Request	XXXX	Customer Special Request Number												

Note:
If other configurations are required, please contact your sale representative.

Sample Standard Application Model Code								
I	II	III	IV	V	VI	VII	VIII	IX
GFC	XX	X	0004-005L	01	C	A	DA	XXXX

Sample Pivotal System Blank Model Code								
I	II	III	IV	V	VI	VII	VIII	IX
GFC	XX	C	PS07-050L	01	C	A	DB	XXXX

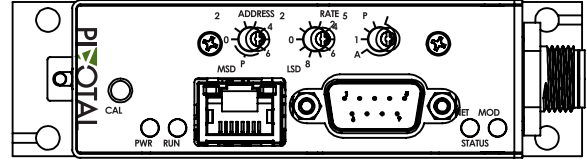
Communication Protocols

Supported Protocols

The GFC supports analog, DeviceNet, RS-485 and Ethercat communication protocols.

Analog and RS-485 Interface

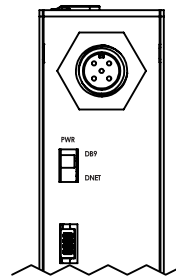
A 9-pin male D-sub connector on top of the GFC enclosure (right) is for operating in the analog and RS-485 modes.



For the analog and RS-485 modes, a suitable mating connector is Tyco PN# 1-747943-6.

DeviceNet Interface

The industry standard, ODVA-compliant DeviceNet *thin* cable with a *micro* connector is located on the side of the GFC enclosure. The table on the right defines this connector's pins.

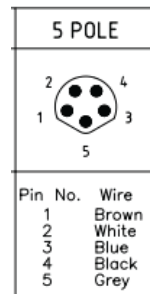


DeviceNet

Pin	Signal Name	Specification
1	Drain	-
2	V+	+11 VDC to +24 VDC
3	V-	0 VDC
4	CAN_H	-
5	CAN_L	-

Ethercat Interface

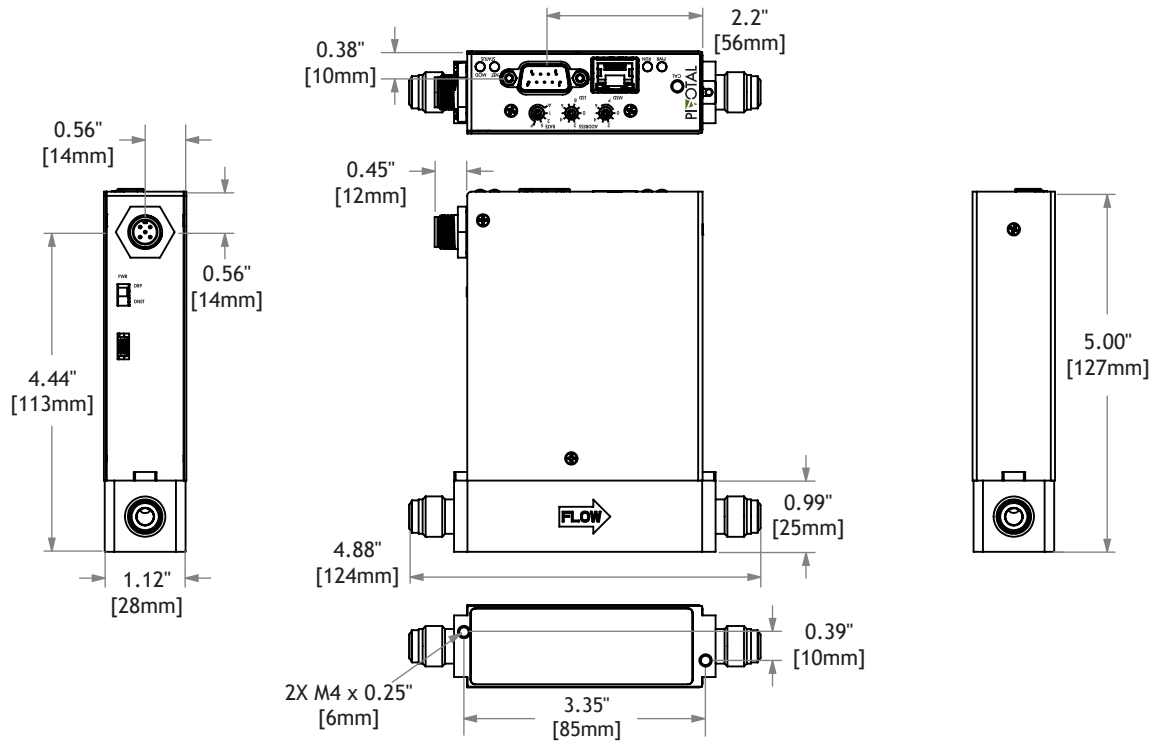
A 5 pin M8 power connector is located on the side of the GFC enclosure. The table on the right defines this connector's pins.



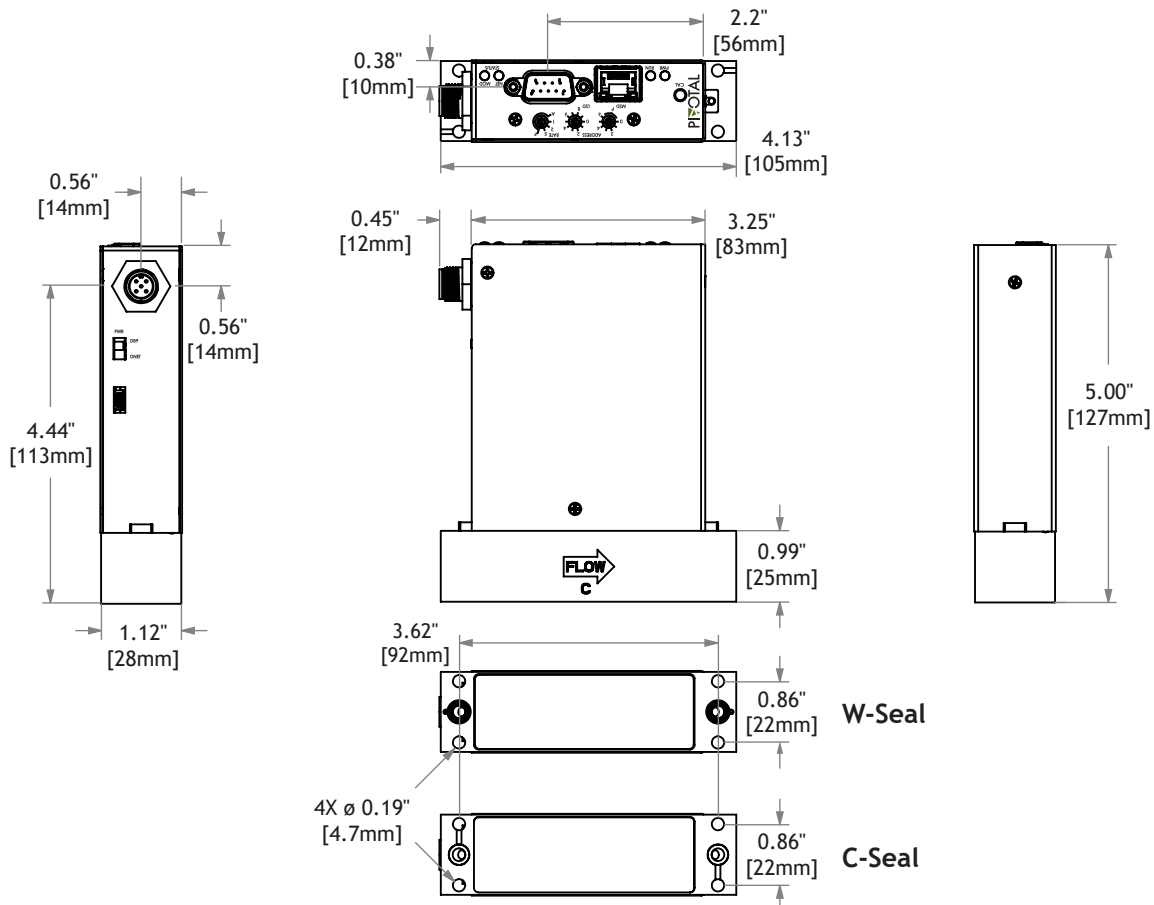
Ethercat

Pin	Signal Name	Specification
1	V+	+24 VDC
2	Chassis Ground	-
3	Power Common	-
4	Unassigned	-
5	Unassigned	-

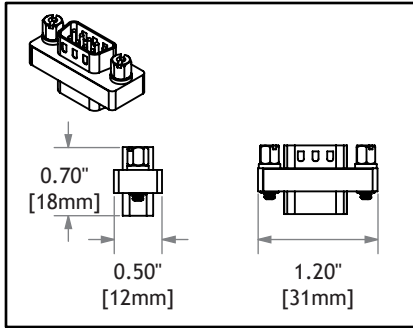
GFC VCR Dimensions



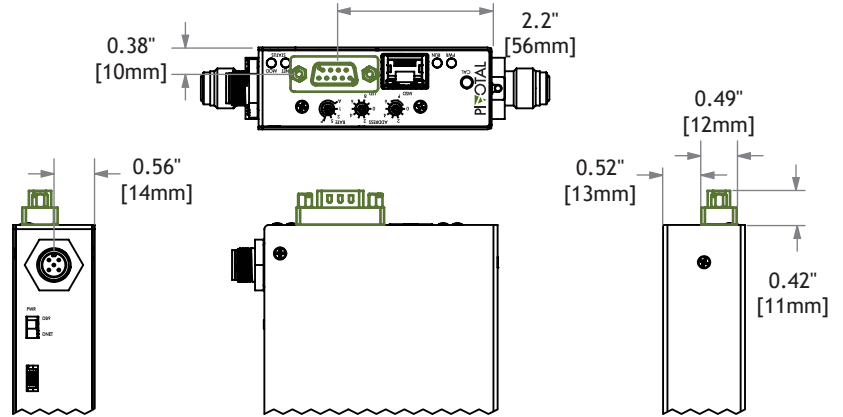
GFC C-Seal and W-Seal Dimensions



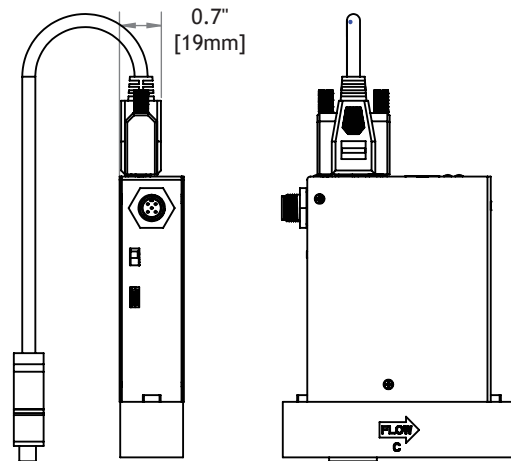
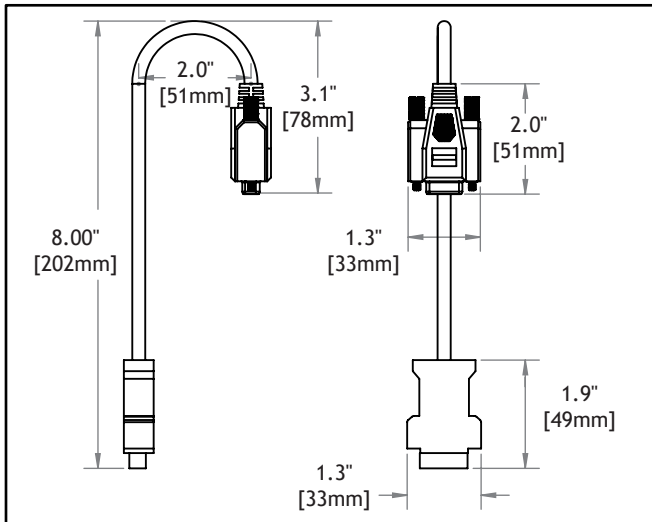
GFC Analog Adapter (AB)



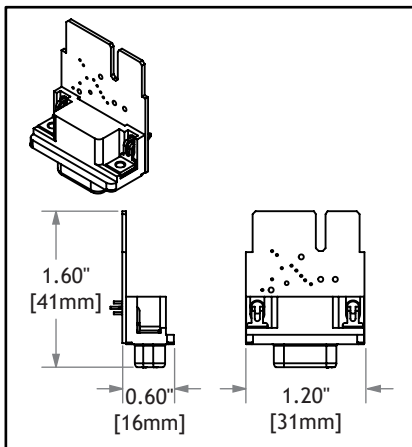
On the right is how the adapter (in green) is attached to the GFC.



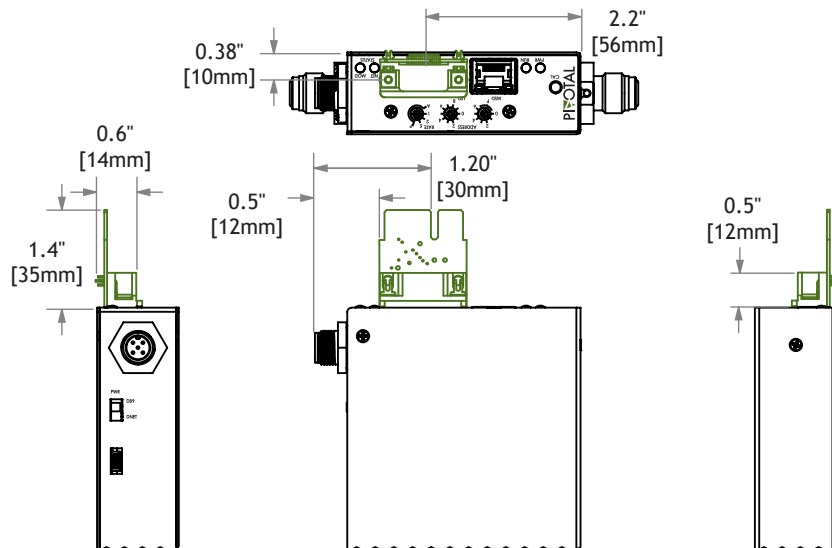
GFC Honda Adapter (AC and AD)



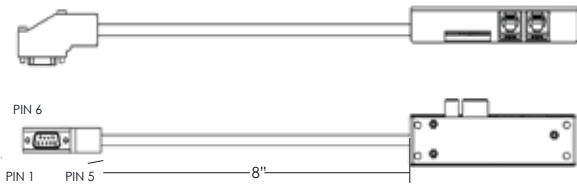
GFC Card Edge Analog Adapter (AE and AF)



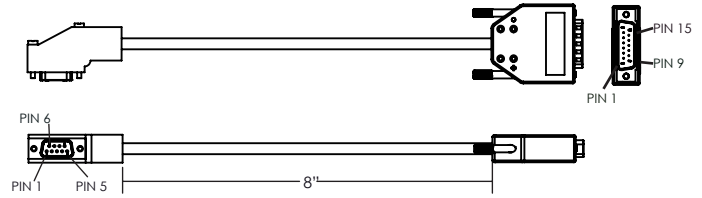
On the right is how the adapter (in green) is attached to the GFC.



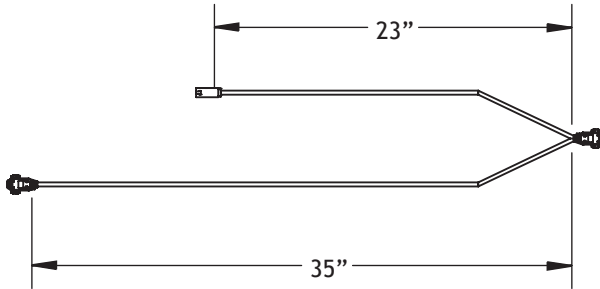
GFC DB9 to Card Edge - RJ11 Cable (AG)



GFC DB9 to DB15 Adapter Cable (AH and AJ)

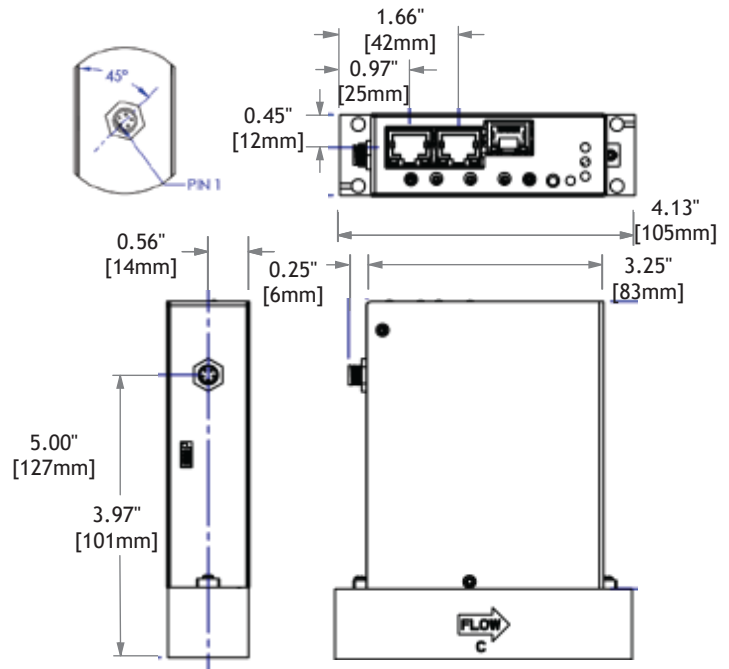


GFC FNET Cable (RC)



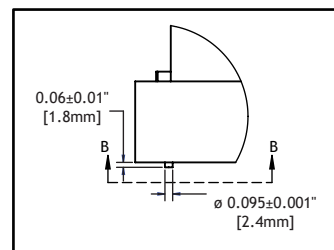
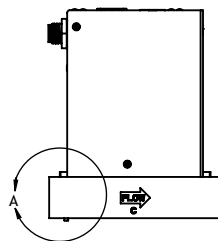
DB9-F	DB9-M	RJ45	Description
1	1	-	Valve Override Signal (Input)
2	2	-	Flow Feedback Signal (Output)
3	3	8	Power Supply +15V
4	4	1, 2	Power Supply 0V
5	5	9	Power Supply -15V
6	6	-	Flow Setpoint Signal (Input)
7	7	-	Signal Common (0V)
8	-	-	RS-485 +
9	-	-	RS-485 -

GFC Ethercat C-Seal and W-Seal Dimensions

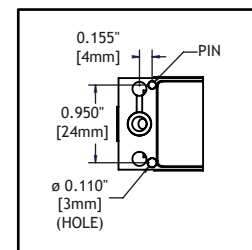


GFC C-Seal Poke Yoke Dimensions

Refer to the GFC C-seal drawing for more detail.



Detail A



Section B-B

About Pivotal

Pivotal Systems Corporation provides best-in-class monitoring and process control technology for the semiconductor manufacturing industry. Pivotal's vision is to enable an order of magnitude increase in fab productivity and capital efficiency for current and future technology nodes. This vision is achieved through its real time in situ process monitoring and control solutions. Founded in 2004 and based in Fremont, California, the company is led by veterans from the semiconductor and high-tech industries. For more information about Pivotal, visit www.pivotal.com or send an email to support@pivotal.com.

Copyright © 2018 Pivotal Systems Corporation. All rights reserved.

Pivotal Systems Corporation
48389 Fremont Boulevard, Suite 100, Fremont, California 94538 USA
T: +1-510-770-9125 • E: support@pivotal.com • W: www.pivotal.com

PIVOTAL
SYSTEMS

10-141-109-5 (Updated May 2018)